



Japan Gases & Facilities Committee Meeting Summary and Minutes

SEMI Japan Standards Fall 2012 Meetings Thursday, September 20, 2012 15:00-17:00 SEMI Japan, Tokyo, Japan

Next Committee Meeting Wednesday, December 5, 2012, 15:00-17:00 SEMICON Japan 2012, Makuhari Messe, Chiba, Japan

Table 1 Meeting Attendees

Co-Chair: Hiromichi Enami (Hitachi High Technologies), Isao Suzuki (MKS Japan) **SEMI Staff:** Naoko Tejima (SEMI Japan)

Company	Last	First	Company	Last	First
Nafco	Doi	Takafumi	Fujikin	Machii	Yoshifumi
Hitachi High Technologies	Enami	Hiromichi	MKS Japan	Suzuki	Isao
Swagelok	Ishida	Noritsugu	SEMI Japan	Naoko	Tejima
Flow Techno Service	Ishihara	Seiji			

* alphabetical order by last name

Table 2 Leadership Changes

None

Table 3 Ballot Results

None

Table 4 Authorized Ballots

#	When	SC/TF/WG	Details
5490		5	Reapproval of SEMI F102-0306, Guide for Selecting Specifications for Dimension of Components for Surface Mount Gas Distribution Systems

Table 5 Authorized Activities

#	Type	SC/TF/WG	Details
5490		2	Reapproval of SEMI F102-0306, Guide for Selecting Specifications for Dimension of Components for Surface Mount Gas Distribution Systems
Note: SNA	Note: SNARFs and TFOFs are available for review on the SEMI Web site at:		

http://downloads.semi.org/web/wstdsbal.nsf/TFOFSNARF





Table 6 New Action Items

Item #	Assigned to	Details
G+F120920-01		To research the background the SNARF of Doc 5446 was submitted and to send the some materials to SEMI staff.
G+F120920-02	SEMI Staff	To prepare SNARFs and SEMI F102 Reapproval ballot for Cycle 7, 2012.

1 Welcome, Reminders and Introductions

Isao Suzuki, committee co-chair, called the meeting to order at 15:00. Self-introductions were made followed by the agenda review.

2 Required Meeting Elements

The meeting reminders on program membership requirement, antitrust issues, intellectual property issues and international effective meeting guidelines, were reviewed by SEMI staff, Naoko Tejima.

3 Review of Previous Meeting Minutes

The committee reviewed the minutes of the previous meeting held on June 29, 2012.

Motion:	To approve the minutes of the previous meeting as written.
By / 2 nd :	Hiromichi Enami (Hitachi High Technologies) / Seiji Ishihara, (Flow Techno Service)
Discussion:	None
Vote:	5 in favor and 0 opposed. Motion passed.

Attachment: 01_JA_G+F_Previous_Mtg_Minutes_120920

4 SEMI Staff Report

Naoko Tejima gave the SEMI staff report. This report included SEMI Global 2012 Calendar of Events, Standards Meeting Schedule in Future, SEMICON Japan 2012, 2012 Critical Dates for SEMI Standards Ballots, SEMI Standards Publications, A&R Recent Review Cycles, Introduction of GoToMeeting, JRSC Planning Meeting and Contact Information.

Attachment: 02_SEMI_Staff_Report_120920

5 Liaison Reports

5.1 North America Gases and Facilities Committee

Naoko Tejima briefly reported for the North America Gases Committee and Facilities Committee. This report included leadership, current committees' organization, meeting information, new SNARFs, inactive standards, ballot results summary, upcoming ballots for Cycle 5 & 6, and committee activities highlights.

• Questions about the need of the development of Doc.5446, Test Method For Determination Of Moisture Dry-Down Characteristics Of Surface-Mounted And Conventional Gas Delivery Systems By Continuous Wave Cavity Ring-Down Spectroscopy (CW-CRDS) was raised. It seems not to be timely.

Action Item: Yoshifumi Machii to research the background the above SNARF was submitted and to send the some materials to SEMI staff.

 Attachment:
 03_NA_Facilities_and_Gases_Comm_Report_120920

 04_Task_Force_Report_F&P_TF_120920

05_Tiger_Optics_CW-CRDS_SEMI_WEST_2012_FMC_120920





5.2 Korea Facilities Committee

Naoko Tejima reported for the Korea Facilities Committee. This report included leadership, current committee organization, meeting information, and updates on Task Force activities.

Attachment: 06_KR_Facilities_Comm_Report_120920

6 Task Force Reports

6.1 F1 Revision Task Force

Yoshifumi Machii reported for the F1 Revision Task Force. Of note:

- SEMI F1-0812, Specification for Leak Integrity of High-Purity Gas Piping Systems and Components was published. Task Force will work on Japanese translation
- The judgment of whether the task force should continue the activities or not will be made at the next committee meeting.

6.2 Gas Panel and Metal Seal Test Methods Task Force

Yoshifumi Machii reported that there were not particular activities.

6.3 5-year-review Task Force

Yoshifumi Machii reported for the 5-year-review Task Force. The Task Force met earlier in the day. Of note:

- SEMI F71 achieve the status of "inactive" in December of 2009. The Task Force judged that it does not need to reinstate its currently "inactive" status.
- SEMI F102-0306, Reapproval of SEMI F102-0306, Guide for Selecting Specifications for Dimension of Components for Surface Mount Gas Distribution Systems is due for 5-year-review. The Task Force suggest to submit reapproval ballot for Cycle 7.

Motion: By / 2 nd :	To approve a new SNARF to reapprove SEMI F102-0306 Hiromichi Enami (Hitachi High Technologies) / Seiji Ishihara (Flow Techno Service)		
Discussion:	None.		
Vote:	5 in favor and 0 opposed. Motion passed.		
Motion:	To submit SEMI F102-0306 Reapproval ballot for Cycle 7, 2012.		
By / 2 nd :	Hiromichi Enami (Hitachi High Technologies) / Seiji Ishihara (Flow Techno Service)		
Discussion:	None.		
Vote:	5 in favor and 0 opposed. Motion passed.		
Action Item:	SEMI staff to prepare SNARFs and SEMI F102 Reapproval ballot for Cycle 7, 2012.		
Attachment:	07_SNARF_of_SEMI-F102_120920		





7 Old Business

7.1 Previous Meeting Action Items

Naoko Tejima reviewed the previous meeting action items.

Table 7 Previous Meeting Actions Items

Item #	Assigned to	Details
G+F120629-01		To forward adjudication result of Doc.5277A through 5290A to the ISC A&R Subcommittee for procedural review Closed
G+F120629-02		To forward adjudication result of Doc.5390 to the ISC A&R Subcommittee for procedural review. Closed
	Yoshifumi Machii (5-year-review TF)	To prepare SNARF and submit to co-chairs via SEMI Staff. Closed

8 New Business

None

9 Action Item Review

9.1 New Action Items

Naoko Tejima reviewed the new action items. These can be found in the New Action Items table at the beginning of these minutes.

10 Next Meeting and Adjournment

The next meeting of the Japan Gases & Facilities Committee is Wednesday, December 5, 2012, 15:00-17:00, in conjunction with SEMICON Japan 2012, Makuhari Messe, Chiba, Japan





Respectfully submitted by: Naoko Tejima Manager, Standards SEMI Japan Phone: +81.3.3222.5804 Email: ntejima@semi.org

Minutes approved by:	
Hiromichi Enami (Hitachi High Technologies), Co-chair	October 25, 2012
Isao Suzuki (MKS Japan), Co-chair	October 25, 2012

Table 8 Index of Available Attachments #1

#	Title
1	JA_G+F_Previous_Mtg_Minutes_120920
2	SEMI_Staff_Report_120920
3	NA_Facilities_and_Gases_Comm_Report_120920
4	Task_Force_Report_F&P_TF_120920
5	Tiger_Optics_CW-CRDS_SEMI_WEST_2012_FMC_120920
6	KR_Facilities_Comm_Report_120920
7	SNARF_of_SEMI-F102_120920

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact Naoko Tejima at the contact information above.